



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 1853
Shoriki NARITA et al. : Docket No. 2001_1876A
Serial No. 10/019,700 : Group Art Unit 2825
Filed January 2, 2002 : Examiner Igwe U. Anya

BUMP FORMING APPARATUS FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVAL
METHOD FOR CHARGE APPEARANCE
SEMICONDUCTOR SUBSTRATE,
CHARGE REMOVING UNIT FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, AND CHARGE APPEARANCE
SEMICONDUCTOR SUBSTRATE

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
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ACCOUNT NO. 23-0975

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RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Restriction Requirement of July 29, 2003, Applicants hereby elect Group I, which is drawn to an apparatus and is embodied by claims 1-13 and 25-39.

Having made the required election, a full examination on the merits of the elected group is requested.

Respectfully submitted,

Shoriki NARITA et al.

By: Michael S. Huppert

Michael S. Huppert
Registration No. 40,268
Attorney for Applicants

MSH/kjf
Washington, D.C. 20006-1021
Telephone (202) 721-8200
Facsimile (202) 721-8250
August 29, 2003

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